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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:
Nilsen et al.

Serial No. 10/616,735

Filed: 07/10/2003

For: Microcomponent Interconnection
Utilizing Post-Assembly Activation

§ Attorney Docket No. 34003.77
§
§ Customer No.: 27683
§
§ Group Art Unit: 2812
§
§ Confirmation No.: 2759
§

SECOND INFORMATION DISCLOSURE STATEMENT

MAIL STOP AMENDMENT
Commissioner For Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

In compliance with the duty of disclosure under 37 CFR §1.56, and in accordance with the practice under 37 CFR §1.97 and §1.98, the Examiner's attention is directed to the documents listed on the enclosed modified Form PTO-1449. No inference should be made that the cited references are in fact material, are in fact prior art, or that no better art exists. The cited patents are listed in numerical order and are not in any order based on their pertinence.

Pursuant to the amendment to 37 CFR 1.98 (a)(2)(i), as stated in an OG Notice dated October 12, 2004, copies of the U.S. patent documents listed on the enclosed modified Form PTO-1449 are not attached.

This Information Disclosure Statement is being filed within three months of the United States filing date or before the mailing date of a first Office Action on the merits. No certification or fee is required (37 CFR §1.97(b)).

It is respectfully requested that the above information be considered by the Examiner and that a copy of the enclosed Form PTO-1449 be returned indicating that such information has been considered.

Respectfully submitted,

DR Hofman

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Karen L. Underwood
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In place of PTO 1449 Form		U. S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		Complete if Known	
SEP 26 2005 INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)		Application Number		10/616735	
		Filing Date		07/10/2003	
		Applicant(s)		Nilsen et al.	
		Art Unit		2812	
		Examiner Name		To be Determined	
SHEET 1 OF 4		Attorney Docket Number		34003.77	

U. S. PATENT DOCUMENTS				
Examiner's Initials	Cite No.	Document Number	Publication Date MM/YYYY	Name of Patentee or Applicant of Cited Document
	A1	3268774	08/1966	Ortner
	A2	3439416	04/1969	Yando
	A3	3467942	09/1969	Dell et al.
	A4	3588618	06/1971	Otte
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	A6	4141138	02/1979	Quick
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	A9	4852242	08/1989	Tella et al.
	A10	4911098	03/1990	Tabata
	A11	4955814	09/1990	Christie et al.
	A12	4963748	10/1990	Szilagyi
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	A14	5025346	06/1991	Tang et al.
	A15	5072288	12/1991	MacDonald et al.
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	A18	5122663	06/1992	Chang et al.
	A19	5160877	11/1992	Fujiwara et al.
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	A21	5273441	12/1993	Volz et al.
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	A44	6239685	05/2001	Albrecht et al.
	A45	6257925	07/2001	Jones

Examiner Signature		Date Considered	
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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include a copy of this form with next communication to applicant.

In place of PTO-1449 Form		U. S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		Complete if Known	
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				Art Unit	2812
				Examiner Name	To be Determined
SHEET	2	OF	4	Attorney Docket Number	34003.77

U. S. PATENT DOCUMENTS

Examiner's Initials	Cite No.	Document Number	Publication Date MM/YYYY	Name of Patentee or Applicant of Cited Document
	A46	6263549	07/2001	Uehara
	A47	20010010348	08/2001	Bilanin et al.
	A48	6300156	10/2001	Decker et al.
	A49	6303885	10/2001	Hichwa et al.
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Examiner's Initials	Cite No.	Foreign Patent Document (Country Code - Number - Kind)	Publication Date MM/YYYY	Patentee or Applicant of Cited Document	Translation Y/N
	B1	JP57161819	10/1982	Yamatake Honeywell KK	English Abstract
	B2	EP0490530	06/1992	Mitsui Toatsu Chemicals	
	B3	EP0497620	08/1992	University Carnegie-Mellon	
	B4	JP05166973	07/1993	Mitsubishi Electric Corp.	English Abstract
	B5	JP06061691	03/1994	Matsushita Electric Ind. Co. Ltd.	English Abstract
	B6	WO 9713981	04/1997	Minnesota Mining & Mfg. Co.	
	B7	DE19746585	04/1999	Merck Patent GMBH	English Abstract and US Equivalent 6488315

NON-PATENT LITERATURE DOCUMENTS

Examiner's Initials	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article, title of the item, date, page(s), volume- issue number(s), publisher, city/country where published
	C1	Arai et al., "A New Pick Up & Release Method By Micromanipulation," IEEE, January 1997.
	C2	Capanu et al., "Design, Fabrication, and Testing of a Bistable Electromagnetically Actuated Microvalve", Journal of Microelectromechanical Systems, Vol. 9, No. 2, June 2000, pp. 181-188.

Examiner Signature		Date Considered	
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	C3	Cohn et al., "Microassembly Technologies for MEMS", University of California at Berkley and University of Washington.
	C4	Cohn et al., "Self-Assembling Electrical Networks: An Application of Micromachining Technology", May 1991.
	C5	Comtois et al., "Applications for surface-micromachined polysilicon thermal actuators and arrays," Sensors and Actuators A58, 1997, pp. 19-25.
	C6	Comtois et al., "Electrothermal actuators fabricated in four-level planarized surface micromachined polycrystalline silicon," Sensors and Actuators A70, 1998, pp. 23-31.
	C7	Comtois et al., "Thermal Microactuators for surface-micromachining processes," SPIE vol. 2642, 1995, pp. 10-21.
	C8	Dechev et al., "Microassembly of 3-D Microstructure Using a Compliant, Passive Microgripper," Journal of Microelectromechanical Systems, vol. 13, No. 2, April 2004, pp. 176-189.
	C9	Ellis, et al., "High aspect ratio silicon micromechanical connectors", High Aspect Ratio Micro-Structure Technology Workshop, Monterey, California, June 15-17, 2003.
	C10	Fearing, "Survey of Sticking Effects for Micro Parts Handling", IEEE, April 1995.
	C11	Gomm et al., "In-Plane Linear Displacement Bistable Microrelay", 2002 IOP Publishing Ltd., UK, pp. 257-264.
	C12	Handbook of Industrial Robotics, Shimon Y. Nof, Editor, Chapter 26 and Section 4.1.4., pp. 478-479.
	C13	Handbook of Industrial Robotics, Shimon Y. Nof, Editor, Second Edition, 1999, Chapter 5, pp. 43-78.
	C14	Hitakawa, "Advanced Parts Orientation System Has Wide Application", August 1988.
	C15	IBM Technical Disclosure Bulletin, "Chip-to-Chip Cable Connection," IBM Corp., Vol. 27, No. 11, April 1985, pp.6761-6763.
	C16	International Preliminary Examination Report in PCT/US01/015011 dated September 13, 2002.
	C17	International Preliminary Examination Report in PCT/US01/15059 dated August 2, 2002.
	C18	International Preliminary Examination Report in PCT/US01/24173 dated January 17, 2003.
	C19	International Search Report in PCT/US01/015011 dated December 3, 2001.
	C20	International Search Report in PCT/US01/15059 dated December 12, 2001.
	C21	Jensen et al., "Design Optimization of a Fully-Compliant Bistable Micro-Mechanism", Proceedings of 2001 ASME International Mech. Eng. Congress and Expo., New York, November 2001, pages 1-7.
	C22	Keller et al., "Hexsil Tweezers for Teleoperated Microassembly", IEEE Micro Electro Mechanical Systems Workshop, 1997, pp. 72-77.
	C23	Keller, "Microfabricated High Aspect Ratio Silicon Flexures, 1998.
	C24	Kruglick et al., "Bistable MEMS Relays and Contact Characterization", University of California Berkeley Sensors and Actuators Center, pp. 1-5.
	C25	Maekoba et al., "Self-Aligned Vertical Mirror and V-Grooves Applied to an Optical-Switch: Modeling and Optimization of Bistable Operation by Electromagnetic Actuation", Sensors and Actuators A 87, 2001, pp. 172.178.
	C26	Mohr, "LIGA-A Technology for Fabricating Microstructures and Microsystems," Sensors and Materials, Vol. 10, No. 6, 1998, pp. 363-373.
	C27	Muray et al., "Advances in Arrayed Microcolumn Lithography", Journal of Vacuum Science and Technology. B, Microelectronics and Nanometer Structures Processing, Measurement and Phenomena: An Official Publication of the American Vacuum Society, Volume 18 (6), November/December 2000, pages 3099-3104. (IRN10495228)
	C28	Prasad et al., "Design, Fabrication, and Characterization of Single Crystal Silicon Latching Snap Fasteners for Micro Assembly", Proc. ASME Int.Mech.Eng. Congress and Expo. (IMECE'95), San Francisco, CA, November 1995.
	C29	Qiu et al., "A Centrally-Clamped Parallel-Beam Bistable MEMS Mechanism", IEEE 2001, pp. 353-356.
	C30	Schreiber et al., "Surface Micromachined Electrothermal V-Beam Micromotors", Proc of 2001 ASME International Mechanical Engineering Congress and Exp., November 11, 2001.
	C31	Search Report in PCT/US01/24173 dated May 17, 2002.
	C32	Szilagyi et al., "Synthesis of Electrostatic Focusing and Deflection Systems," JVST B, 15(6), November/December 1997, p. 1971

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